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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10030657	FILING DATE 01/11/2002	CLASS 371	SUBCLASS 1402	GAUS 1402	EXAMINER Le
**APPLICANTS: Wakamatsu Satoru; Oda Hiroyuki; 1773					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP01/03865 05/09/2001					
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** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-139023 05/11/2000					
PG-PUB		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO 1691-0170P	
TITLE : Polycrystalline silicon and process and apparatus for producing the same					
U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	
		Print Claim for O.G.	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
		PREPARED FOR ISSUE	
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